

MAY 17 2006

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:	Hong-Jyh Li	Examiner:	Phillip A. Johnston
Serial No.:	10/816,503	Group Art Unit:	2881
Filed:	April 1, 2004	Docket No.:	2004P51130US/I331.128.101
Title:	PLASMA ION IMPLEMENTATION SYSTEM		

AMENDMENT/REPLY

Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

This Amendment/Reply accompanies the Request for Continued Examination (RCE) 37 CFR 1.114 and is in reply to the Final Office Action mailed March 17, 2006. Please amend the above-identified patent application as follows: